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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

INOUE et al.

Serial No.:

09/698,185

Filed:

October 30, 2000

For:

SEMICONDUCTOR DEVICE AND METHOD FOR

MANUFACTURING THE SAME

Group:

2827

Examiner:

L. Thai

March 19, 2003

SUPPLEMENTAL AMENDMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

In supplement to the Amendment filed on March 17, 2003, please further amend the above-identified application as follows:

In the Specification:

Page 16, paragraph beginning at line 11, has been rewritten as indicated below:

In Fig. 1, a film appears 50 micrometers thick at a horizontal distance of 500 micrometers from one edge of the stress relaxation layer 5. Hence, the average gradient is 10%. The redistributing wire 4 is made of an electrical conductor such as copper. The redistributing wire 4 connects the aluminum pad 7 to a protrusive electrode and a bump pad 3 on a surface of the stress relaxation layer 5. A gold plating 2 for preventing the bump pad 3 from being oxidized may be provided on the bump pad 3. While a dicing area 24 is provided for dicing the wafer 9 having